

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Jurgensen et al.

Group Art Unit:

Serial No.:

Filed:

Attorney Docket No: 98-058/1D

For: Confinement Device for Use in Dry
Etching of Substrate Surface and
Method of Dry Etching a Wafer
Surface

2A
8-3-01PRELIMINARY AMENDMENT

Hon. Commissioner of Patents and Trademarks
Washington, D.C. 20231

Dear Sir:

Prior to examination, please amend the application as follows:

IN THE CLAIMS

Please cancel claims 1-21.

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